

AMENDMENTS TO THE CLAIMS

Claim 1 (Original) A substrate transport apparatus comprising:

 a substrate transport pod that can be sealed hermetically for holding substrates therein, which are taken out from a processing apparatus;

 at least one of a particle filter, a chemical filter, and a dehumidifying apparatus for removing, respectively, particulate substances, chemical substances, and moisture from a gas circulated inside the pod;

 a gas circulation apparatus for circulating a purified gas or purge means;

 a holding apparatus for holding the substrates;

 data storing means; and

 a power supply for driving the dehumidifying apparatus and/or the circulation apparatus and the data storing means.

Claim 2 (Original) A substrate transport apparatus according to claim 1, wherein said data storing means is provided for controlling an operation of the dehumidifying apparatus and/or the circulation apparatus.

Claim 3 (Original) An apparatus according to claim 1, further comprising:

 an identifier ID for distinguishing individual pods; and

 means for sending and receiving control information with outside data storing means.

Claim 4 (Original) A substrate transport apparatus according to claim 1, wherein the pod has means for receiving external signals, and controls internal environment in the pod according to the external signals.

Claim 5 (Original) A substrate transport apparatus according to claim 1, wherein an internal environment of the pod is controlled by sending and receiving information between the pod and a processing apparatus.

Claim 6 (Original) A substrate transport apparatus according to claim 1, wherein the pod is provided with processing history management information on substrates in said data storing means.

Claim 7 (Original) A substrate transport apparatus according to claim 6, wherein the processing history management information is transferred from one pod to other pod.

Claim 8 (Original) A substrate transport apparatus according to claim 6, wherein the processing history management information is communicated by way of a host computer network.

Claim 9 (Original) A substrate transport apparatus according to claim 6, wherein the processing history management information is transferred from one pod to other pod by a controller provided on a processing apparatus.

Claim 10 (Original) A substrate transport apparatus according to claim 6, wherein the processing history management information is transferred from a pod used in a preceding step to a pod to be used in a succeeding step.

Claim 11 (Original) A substrate transport apparatus according to claim 1, wherein an information on a pod to be washed is stored in the data storing means.

Claim 12 (Original) A substrate transport apparatus according to claim 11, wherein said information is sent to a pod washing machine so that the pod can be selected and subjected to washing.

Claim 13 (Original) A substrate transport apparatus according to claim 1, wherein a change of information stored in said data storing means is conducted by communication with outside data storing means by signal input/output portion.

Claim 14 (Original) A substrate transport apparatus according to claim 6, wherein a change of the processing history management information is conducted by signal input/output portion by sending and receiving information with outside data storing means.

Claim 15 (Original) A substrate transport apparatus according to claim 6, wherein a change of lot processing history management information is conducted by signal input/output portion by sending and receiving information with outside data storing means.

Claim 16 (Original) A substrate transport apparatus according to claim 1, wherein a washing interval information of the pod is stored in said data storing means.

Claim 17 (Original) A substrate transport apparatus according to claim 1, wherein a filter change interval information, or an information of a secondary battery is stored in said data storing means.

Claim 18 (Original) A substrate transport apparatus according to claim 17, wherein the filter change interval information of a pod is managed from a product of a processed gas volume and an operation time of the circulation apparatus or the dehumidifying apparatus.

Claim 19 (Original) A substrate transport apparatus according to claim 16, wherein the washing interval information is estimated from an operation time of the gas circulation apparatus.

Claim 20 (Original) A substrate transport apparatus according to claim 1, wherein residual power of a secondary battery provided for the pod is measured, and charged to a necessary level of power.

Claim 21 (Original) A substrate transport apparatus according to claim 6, wherein the processing management history information on individual pod is communicated by wire or radio transmission through a network.

Claim 22 (Original) A substrate transport apparatus according to claim 2, wherein an information on the pod to be washed is sent to a pod washing machine so that the pod can be selected and subjected to washing.

Claim 23 (Original) A substrate transport pod for containing, storing or transporting substrates, comprising:

a pod main body and a door for hermetic sealing of the pod main body, which is formed primarily of a material having moisture absorption coefficient of not more than 0.1%, wherein the pod main body is in contact with the substrates directly or indirectly and has a conductive part so as to enable static charges to be drained from the pod main body; and

a sensor provided for detecting whether the door is opened or closed;

wherein a gas circulation apparatus and/or a dehumidifying apparatus is installed in said pod main body, and is controlled to operate by detecting that the door is closed or opened.

Claim 24 (Original) A substrate transport pod for containing, storing or transporting substrates, comprising:

a pod main body and a door for hermetic sealing of the pod main body, which is formed primarily of a material having moisture absorption coefficient of not more than 0.1%, wherein the pod main body is in contact with the substrates directly or indirectly and has a conductive part so as to enable static charges to be drained from the pod main body; and

a sensor provided for detecting presence of the substrates;

wherein a gas circulation apparatus and/or dehumidifying apparatus is controlled to operate in accordance with detection signal of the sensor for detecting the presence of the substrates.

Claim 25 (New) A method for manufacturing a semiconductor device by transporting substrates between a plurality of processes, comprising:

coating a phot-resist on a semiconductor substrate;
loading the semiconductor substrate into a pod; and
prioritizing a reduction of base substances in said pod so as to suppress a T-top formation.

Claim 26 (New) The method of claim 25, wherein said pod is used for transporting the semiconductor substrates between manufacturing processes in a floor, between floors inside a plant, and between plants, or for storing the semiconductor substrates.

Claim 27 (New) The method of claim 25, wherein said pod is used for transporting the semiconductor substrates between a resist coating process, an exposure process, and a development process.

Claim 28 (New) A substrate transport pod for containing, storing or transporting substrates, comprising:

a pod main body for loading the substrates therein;
a door for hermetic sealing of the pod main body; and
control means for prioritizing reduction of base substances in said pod;
wherein said pod is used in an apparatus in which resist coating, exposure, and development are not continuously performed at an interface section thereof.

Claim 29 (New) The pod of claim 28, wherein a level of ammonia inside said pod is less than $1\mu\text{g}/\text{m}^3$.